

Patent
Attorney's Docket No. 001425-108

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)	
Ge XU et al.)	Group Art Unit: 1763
Application No.: 09/863,338)	Examiner: S. MacArthur
Filed: May 24, 2001)	Confirmation No.: 1018
For: CVD APPARATUS)	VIA FACSIMILE

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AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Official Action dated February 13, 2003, please amend the
above-identified patent application as follows:

IN THE CLAIMS:

Please amend claims 1, 17, 23 and 24 as follows:

1. (Amended) A CVD apparatus comprising:

a vacuum vessel having an inside in which plasma is produced to generate active
species, and film deposition is performed on a substrate by using the active species and a
reactive gas;

an electrically-conductive partitioning wall section formed in the vacuum vessel for
separating the inside thereof into two chambers;